

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

DEC 27 2002

In re Patent Application of:

Kazuichiro ITONAGA et al.

Serial No. 09/662,004

Filed: September 14, 2000

For: METHOD OF FORMING INSULATING
FILM AND METHOD OF FABRICATING
SEMICONDUCTOR DEVICE

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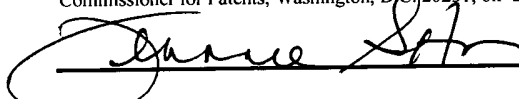
Group Art Unit: 2800

Examiner: William M. Brewster

Date: December 12, 2002

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on December 12, 2002


Jeanne Saxton

RESPONSE TO RESTRICTION/ELECTION REQUIREMENT

Commissioner for Patents
Washington, D.C. 20231

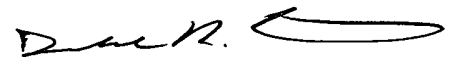
Sir:

In response to the Office Action December 3, 2002 Applicants provide the following election.

Applicant hereby elects Species I, claims 1-12, controlling a thickness and temperature of an insulating film.

Should the Examiner believe a conference would be of benefit in expediting the prosecution of the instant application, he is hereby invited to telephone counsel to arrange such a conference.

Respectfully submitted,



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